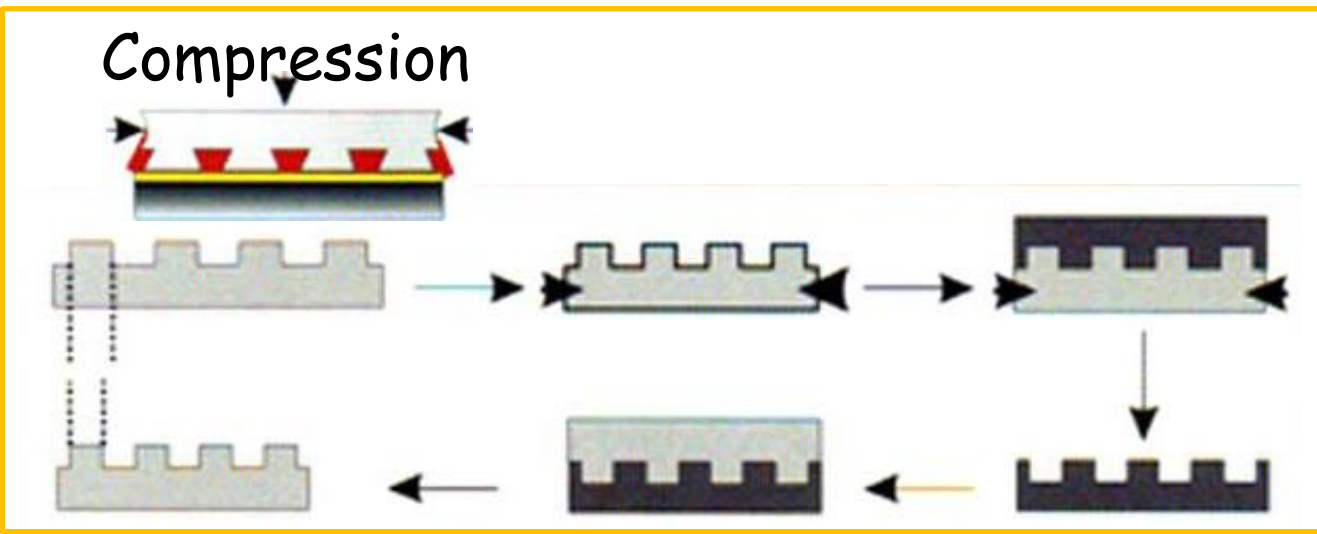
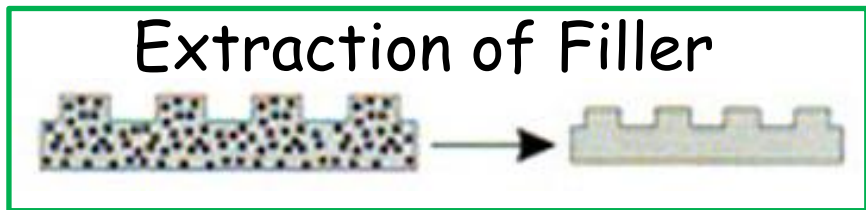
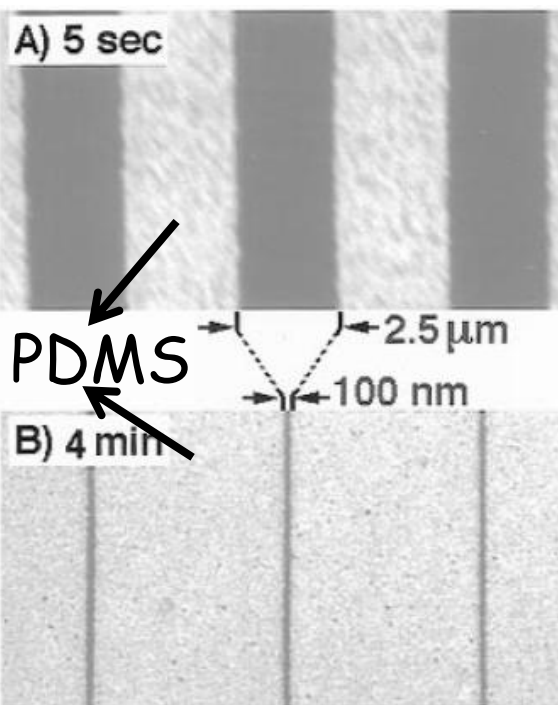


Extending Resolution of Soft Lithography

Methods to Reduce Feature Size:

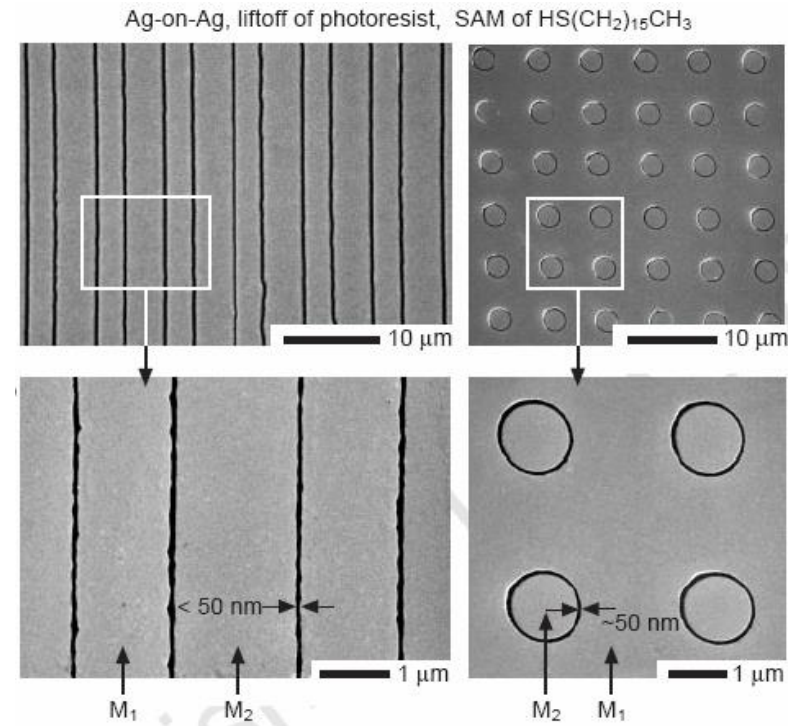
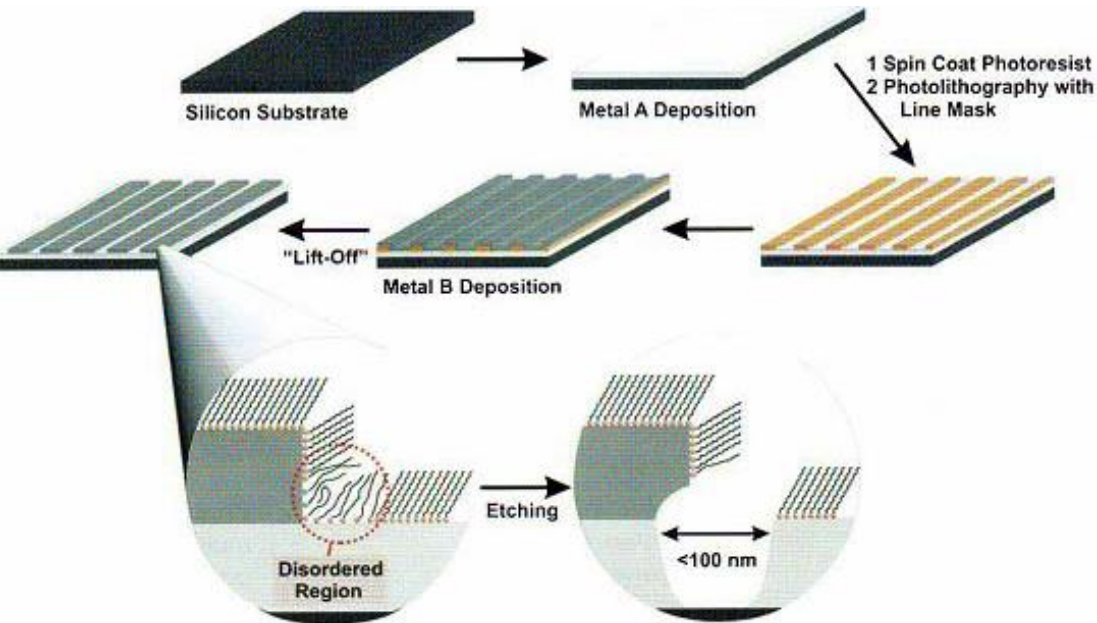


Reactive Spreading



Defect Patterning

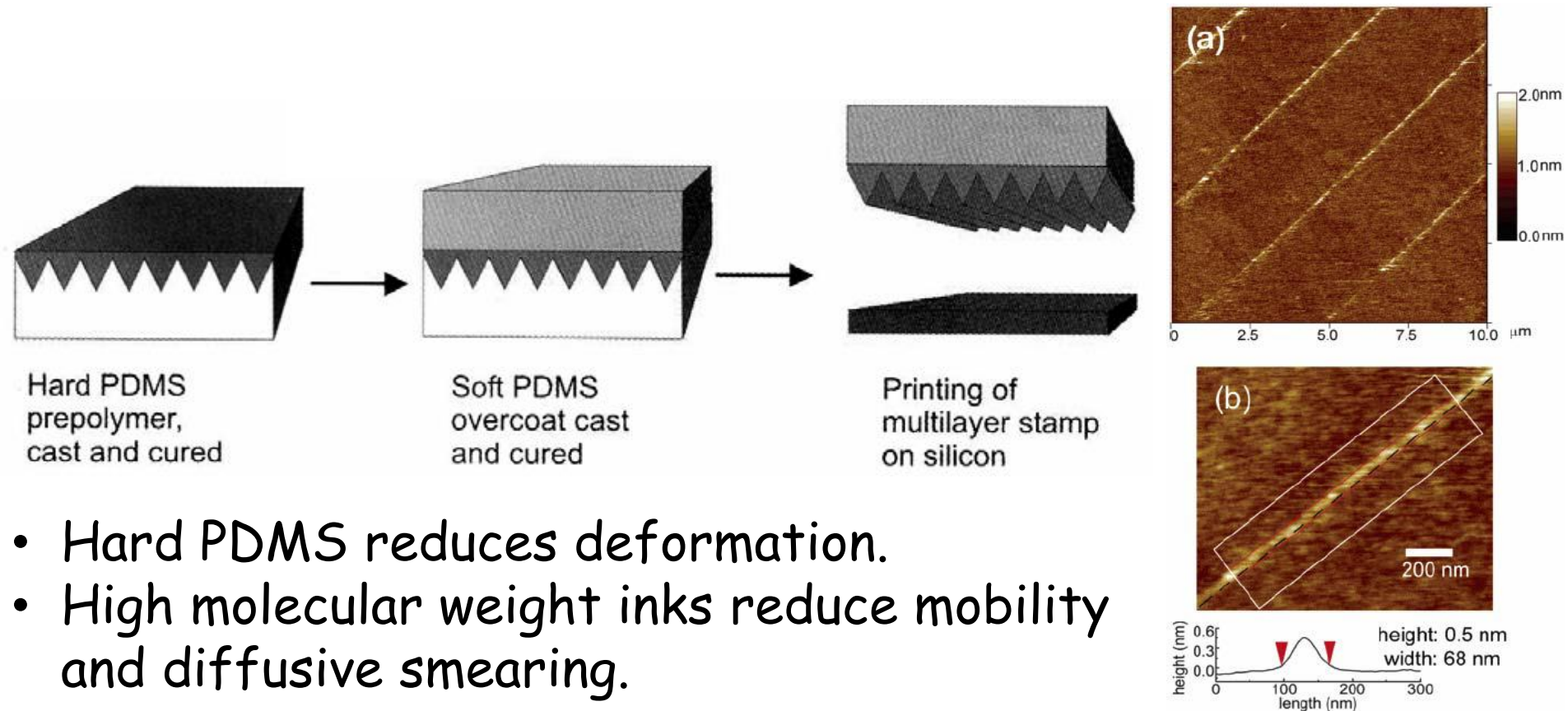
Topologically Directed Etching



Local Disorders in SAMs:

- High disorders in the transition region between two planar surfaces.
- Higher disorders lead to less etch resisting.

Below 30 nm Nanocontact Printing



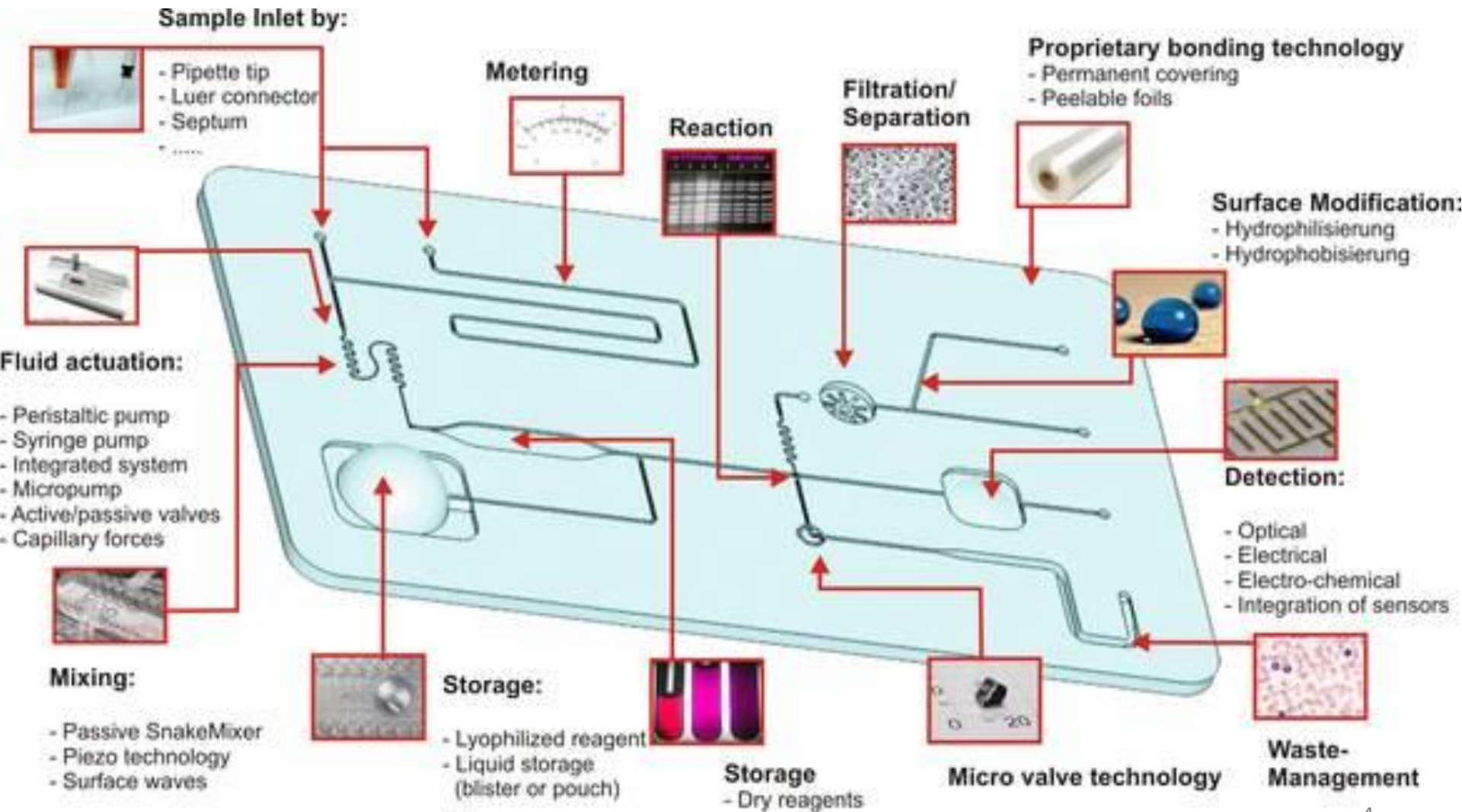
- Hard PDMS reduces deformation.
- High molecular weight inks reduce mobility and diffusive smearing.

Printed titin multimer protein lines on Si

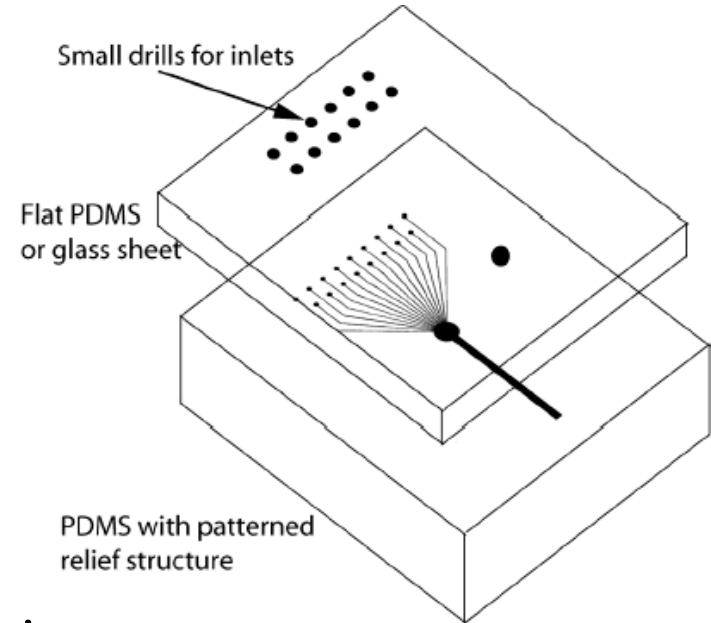
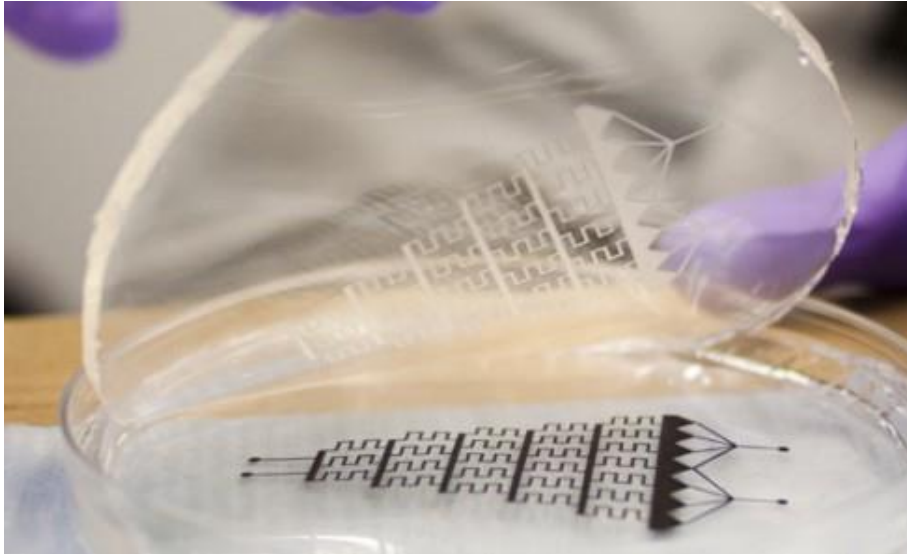
Langmuir **19**, 1963 (2003)



Soft Lithography for Microfluidics



Microfluidic Channels

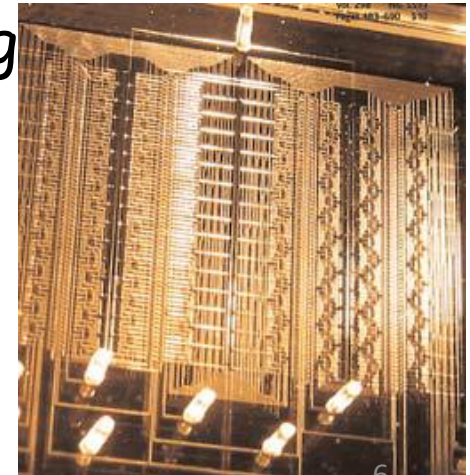
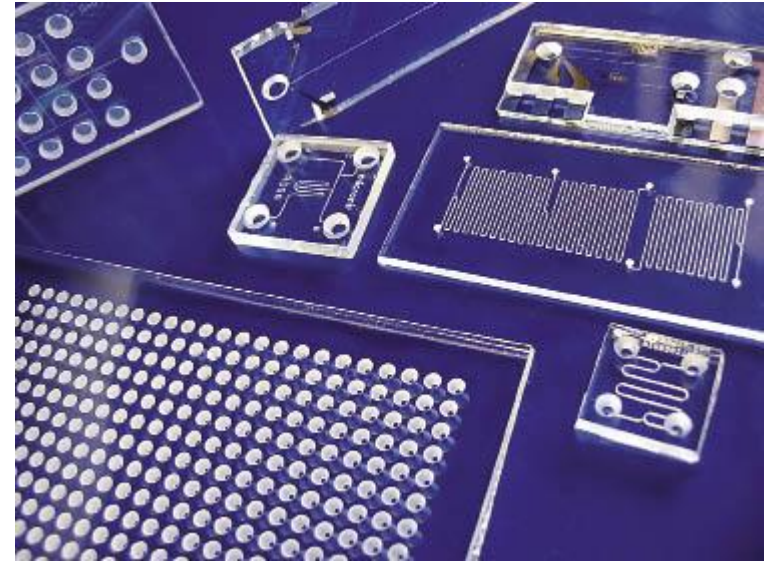
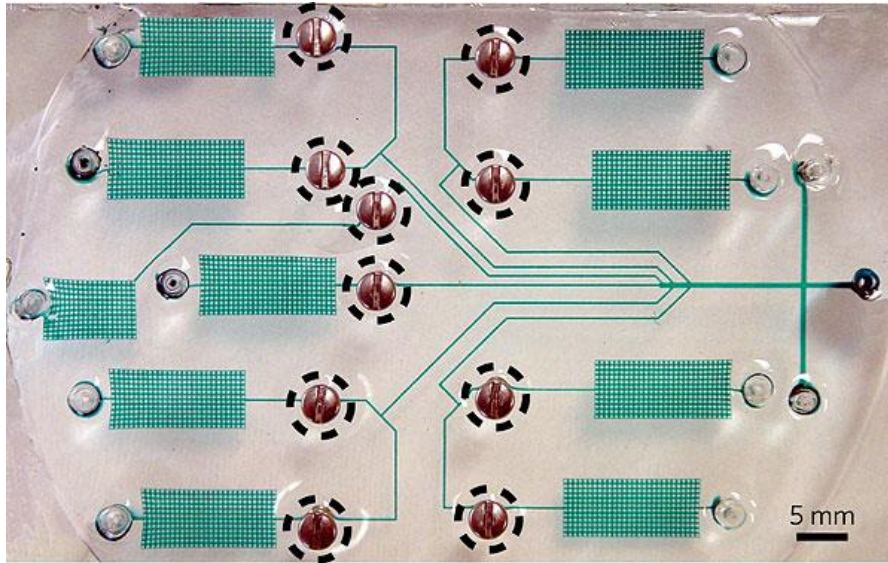


Fabrication of microfluidic channels:

- PDMS piece is released from the master.
- Bond a standard glass slide on top of it.
- Typical microchannel width: tens of micrometers.
- The thickness of the channel is controlled by the thickness of the photoresist.



Soft Lithography for Microfluidics

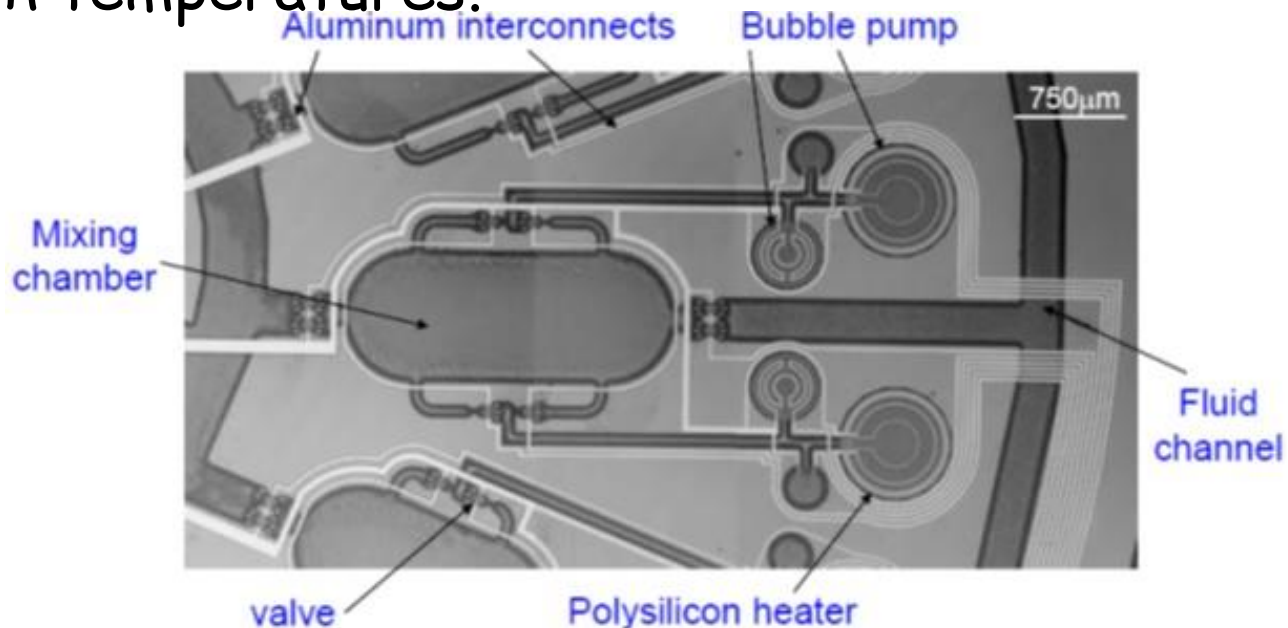


- Soft lithography is well suited for generating microfluidic channels in PDMS.
- Microfluidic channel finds applications in
 - CPU cooling
 - Lab-on-a chip devices
 - Bio-sensors

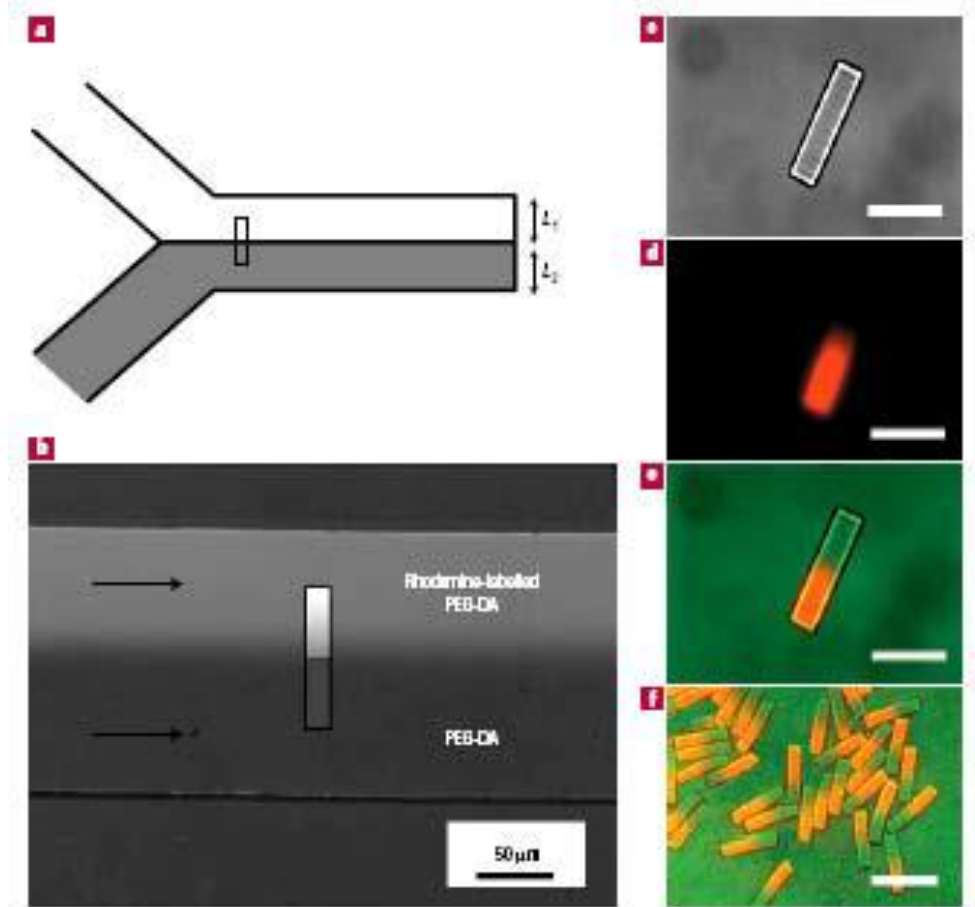
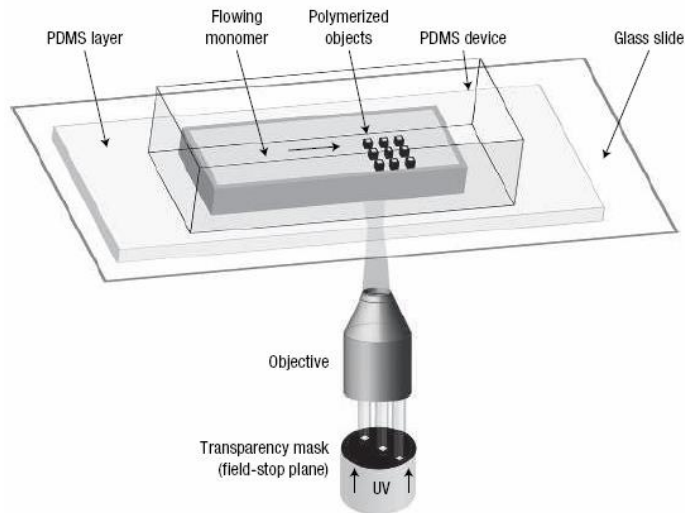


PDMS Channel Advantages

- The PDMS Channels have advantages over Si or glass channels:
 - Inexpensive
 - Flexible and durable
 - Simple to prototype
- Disadvantages: unstable in contact with some organic solvents and at high temperatures.



Making Janus Particles



Reynolds number (Re) - a dimensionless parameter that describes a fluid's tendency to be turbulent.

$$Re = v l \rho / \eta$$

$$Re \sim 1 \ll 2000$$

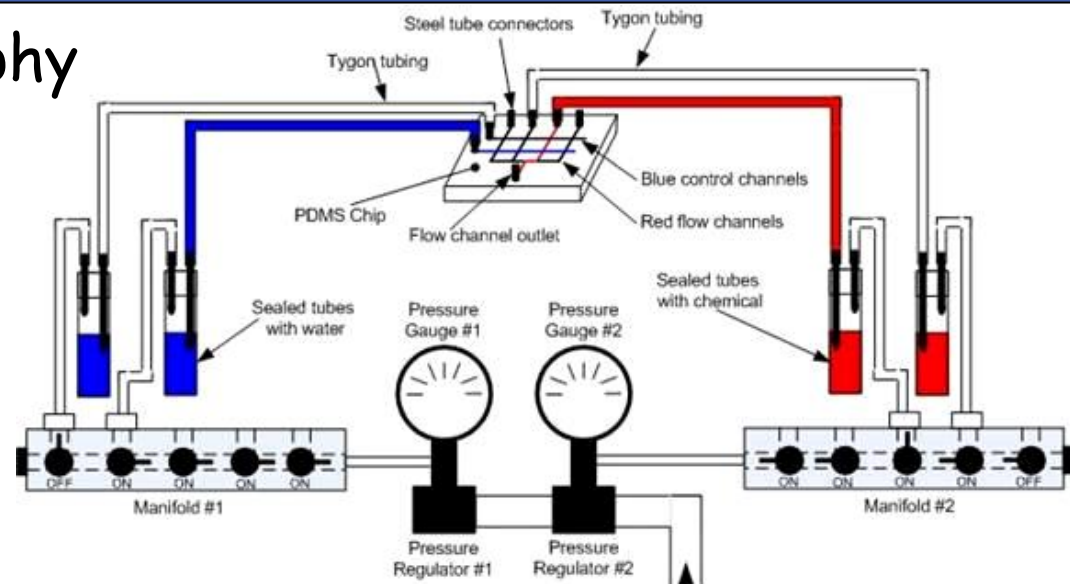
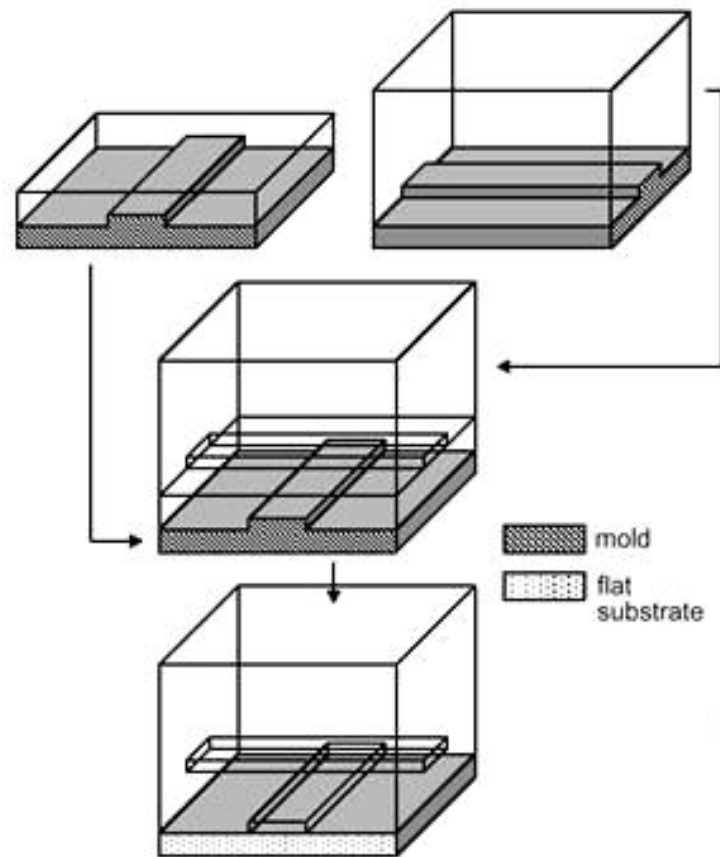
Laminar Flow!

Janus particles

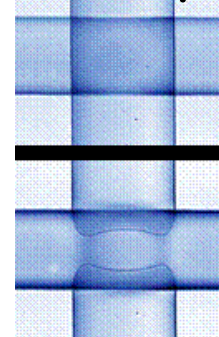
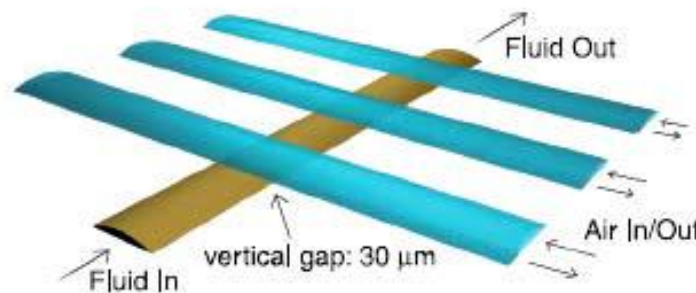


Multilayer Soft Lithography - Microvalves

Multilayer Soft Lithography



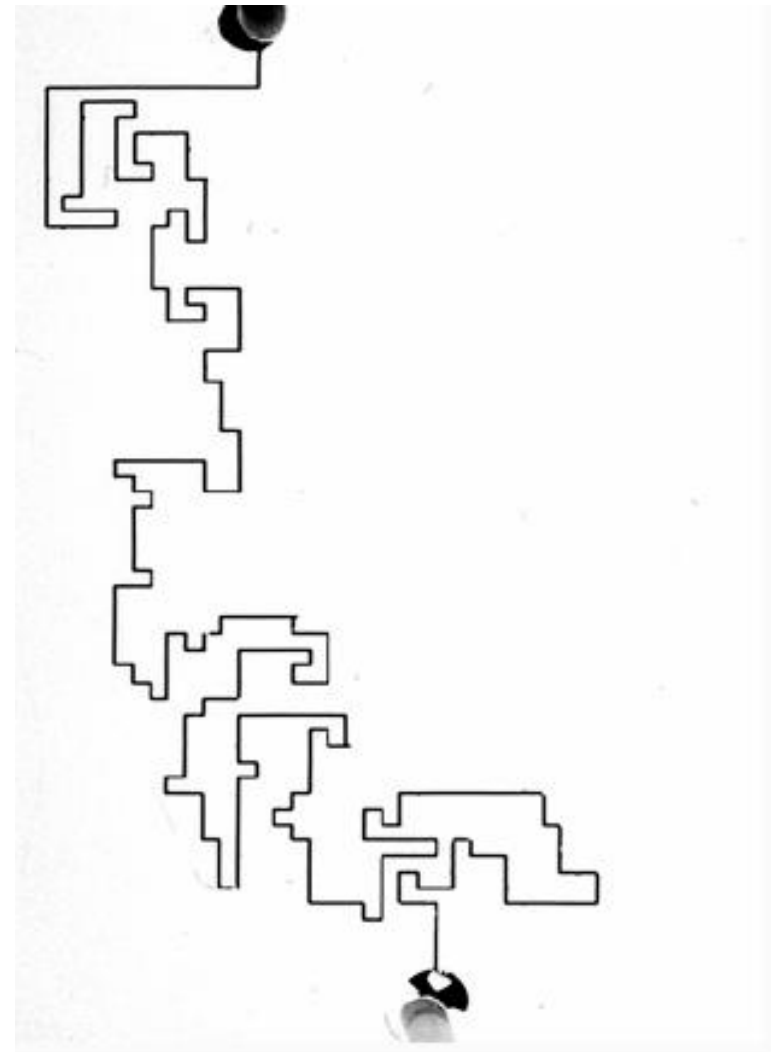
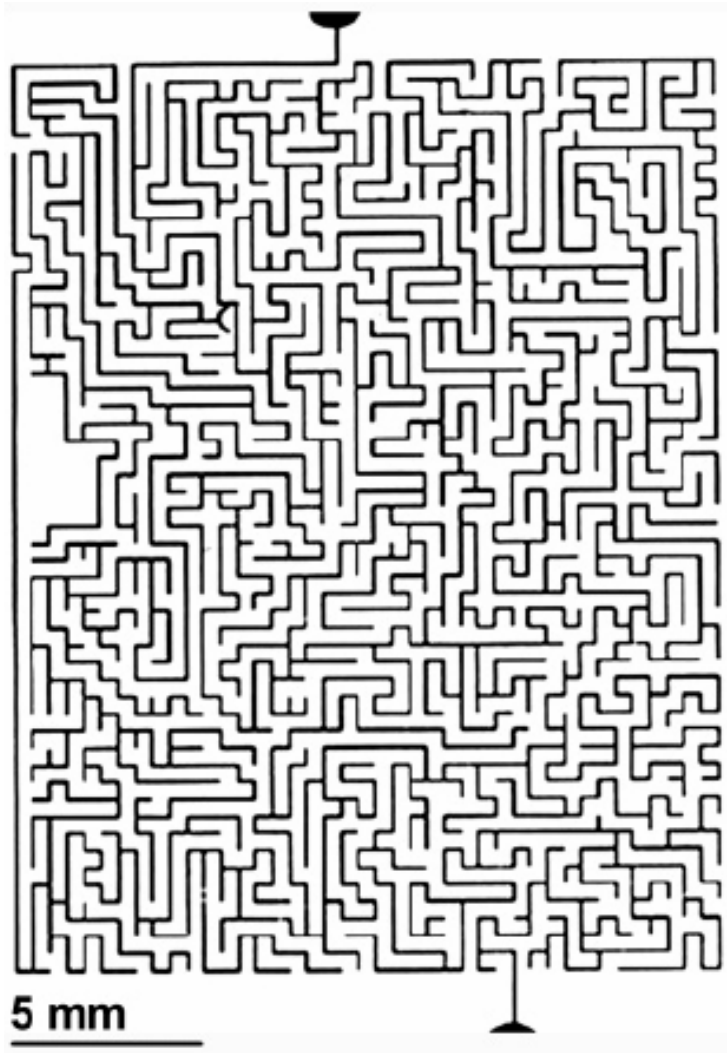
$P = \text{atmosphere}$



$P = 200 \text{ kPa}$



Microfluidics: Solving Mazes

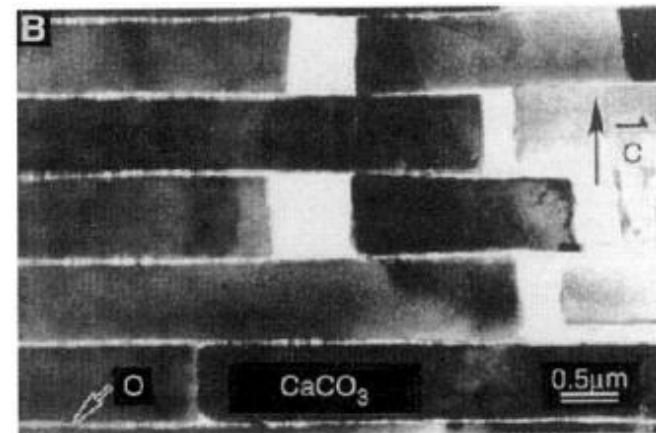
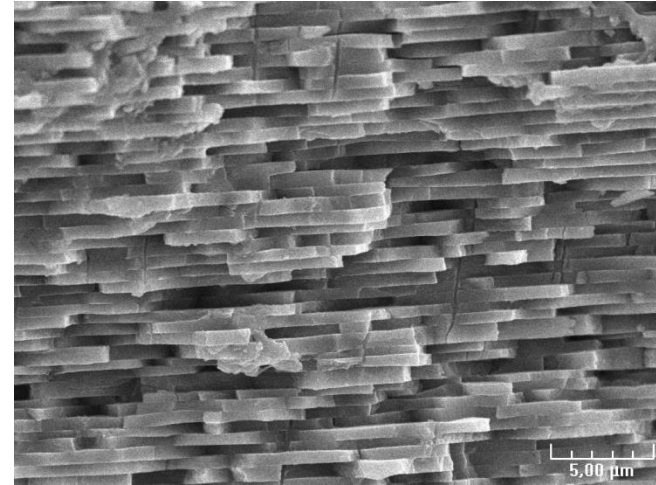


Langmuir **19**, 4714 (2003)



Nature Mazes

Iridescent Nacre Nautilus



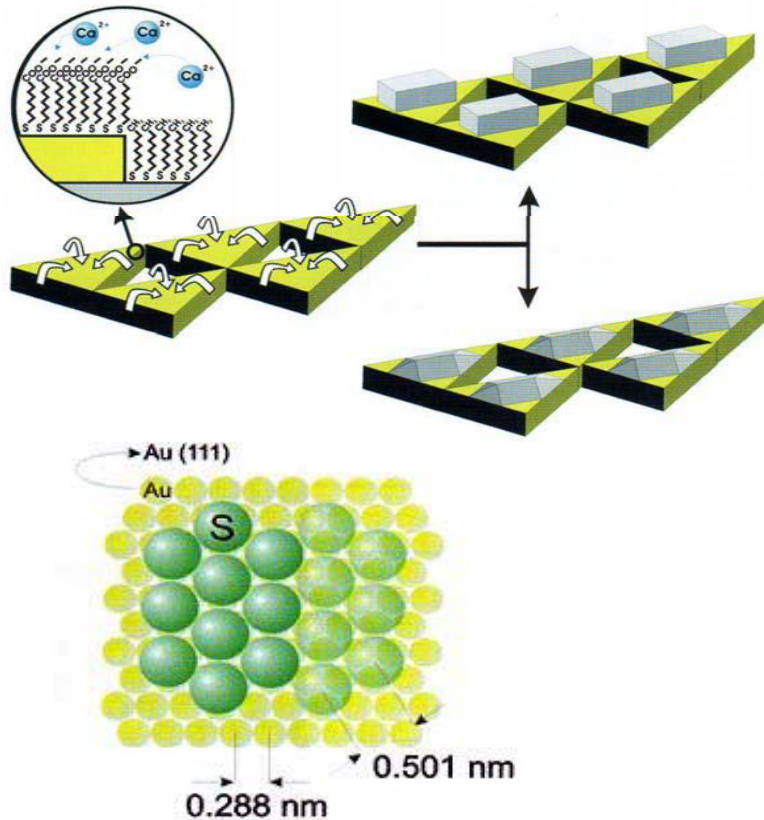
Nature 412, 819 (2001)



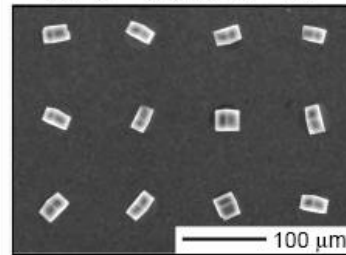
Nanocontact Printing



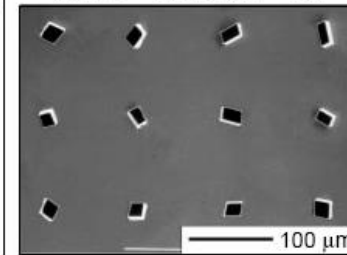
SAMs Controlled Mineralization



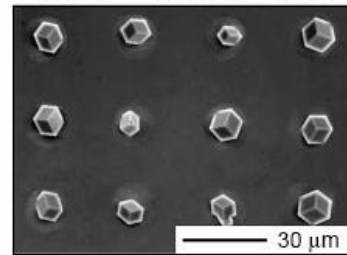
a HS(CH₂)₁₅CO₂H on Au
Nucleating plane (015)
 $d = 35 \mu\text{m}$; $p = 100 \mu\text{m}$
[Ca²⁺] = 10 mM; $N = 100$



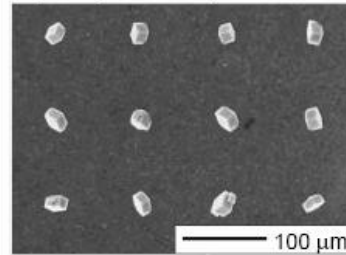
b HS(CH₂)₂₂OH on Au
Nucleating plane (0104)
 $d = 50 \mu\text{m}$; $p = 100 \mu\text{m}$
[Ca²⁺] = 10 mM; $N = 100$



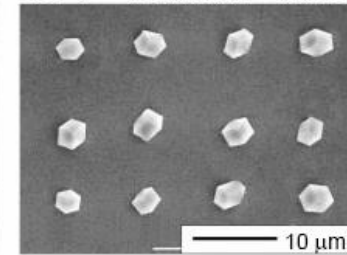
c HS(CH₂)₁₁SO₃H on Pd
Nucleating plane (001)
 $d = 15 \mu\text{m}$; $p = 30 \mu\text{m}$
[Ca²⁺] = 10 mM; $N = 1,000$



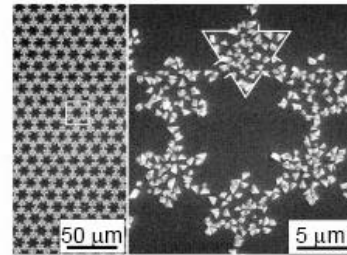
d HS(CH₂)₁₅CO₂H on Ag
Nucleating plane (012)
 $d = 15 \mu\text{m}$; $p = 100 \mu\text{m}$
[Ca²⁺] = 10 mM; $N = 100$



HS(CH₂)₁₅CO₂H on Ag
Nucleating plane (012)
 $d = 3 \mu\text{m}$; $p = 10 \mu\text{m}$
[Ca²⁺] = 100 mM; $N = 10,000$

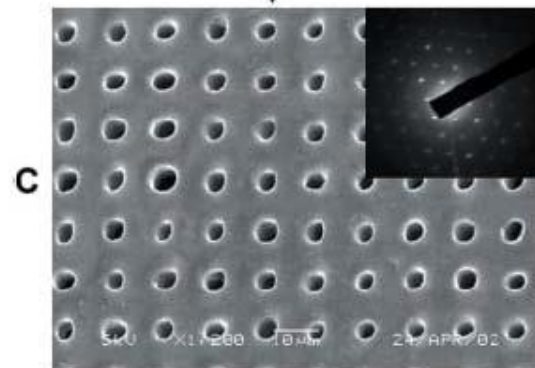
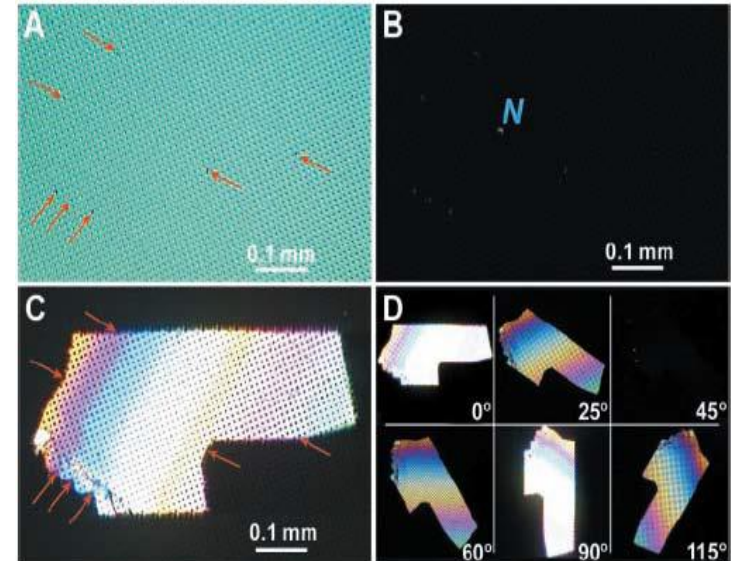
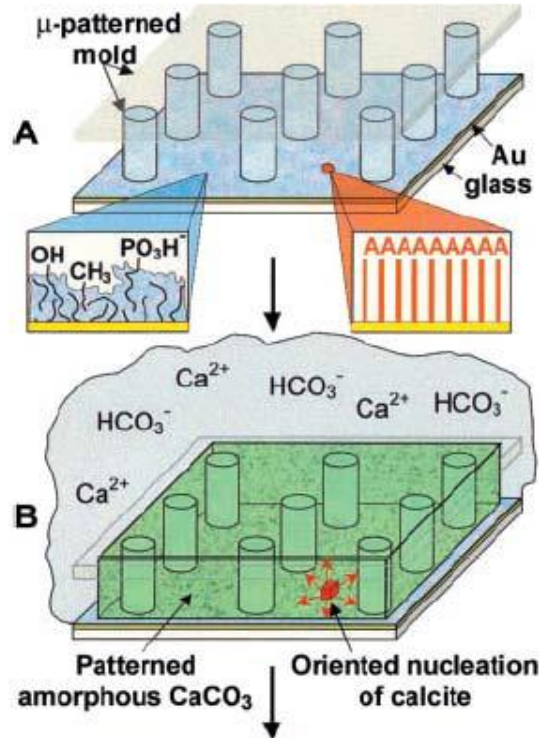


e HS(CH₂)₁₅CO₂H (triangles) +
HS(CH₂)₁₅CH₃ (stars) on Ag
[Ca²⁺] = 100 mM



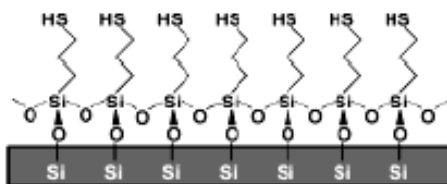
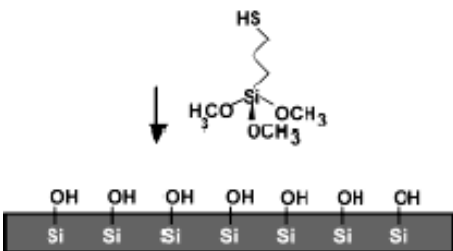
- The densities of nucleation, uniform sizes and crystallographic orientation are controlled by the micropatterned SAMs.
- Nucleation stems form a match between the pattern and orientation of ions adsorbed on the organic surface.

SAMs Directed Growth of Large Single Calcite Crystals

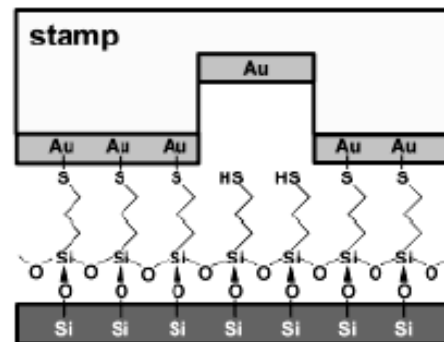


- $A = \text{OH}, \text{CO}_2\text{H}, \text{SO}_3\text{H}$.
- Site-specific nucleation of a nascent calcite crystal occurred at the imprinted SAM nanoregion.
- Micropatterned frameworks act as sites for stress release.

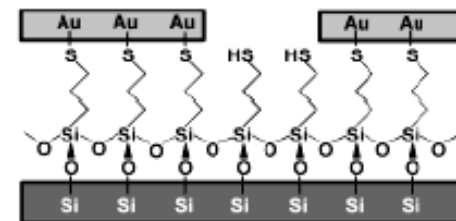
Transfer Printing of Thin Films



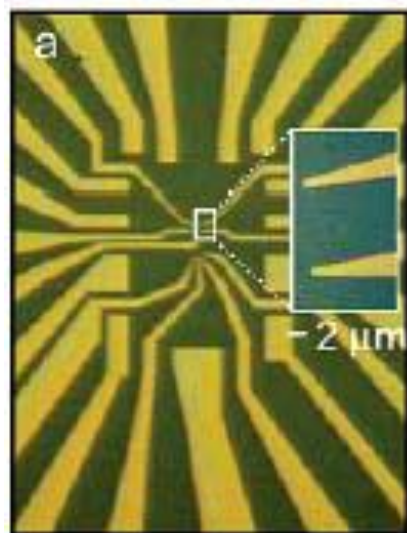
Vapor deposit SAM



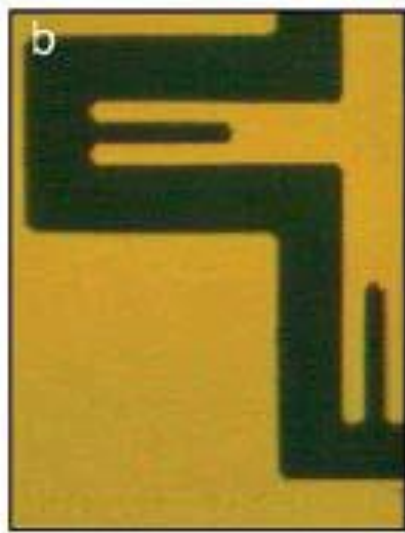
Print with Au-coated stamp



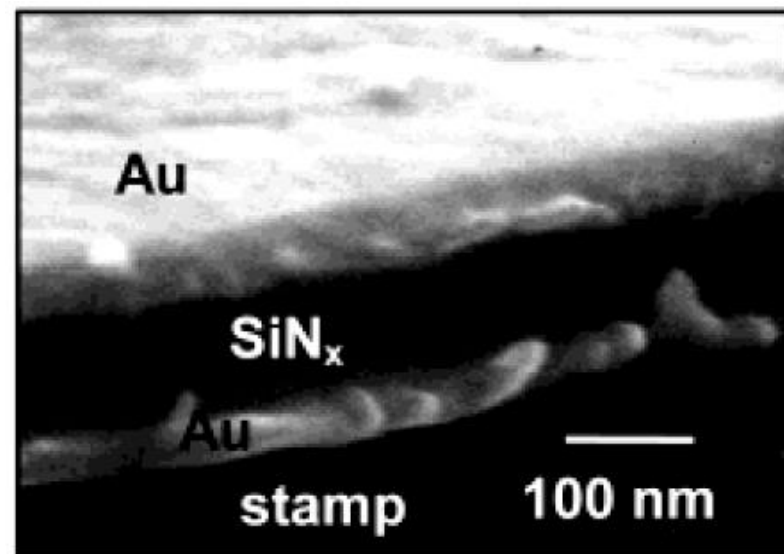
Remove stamp



On Si



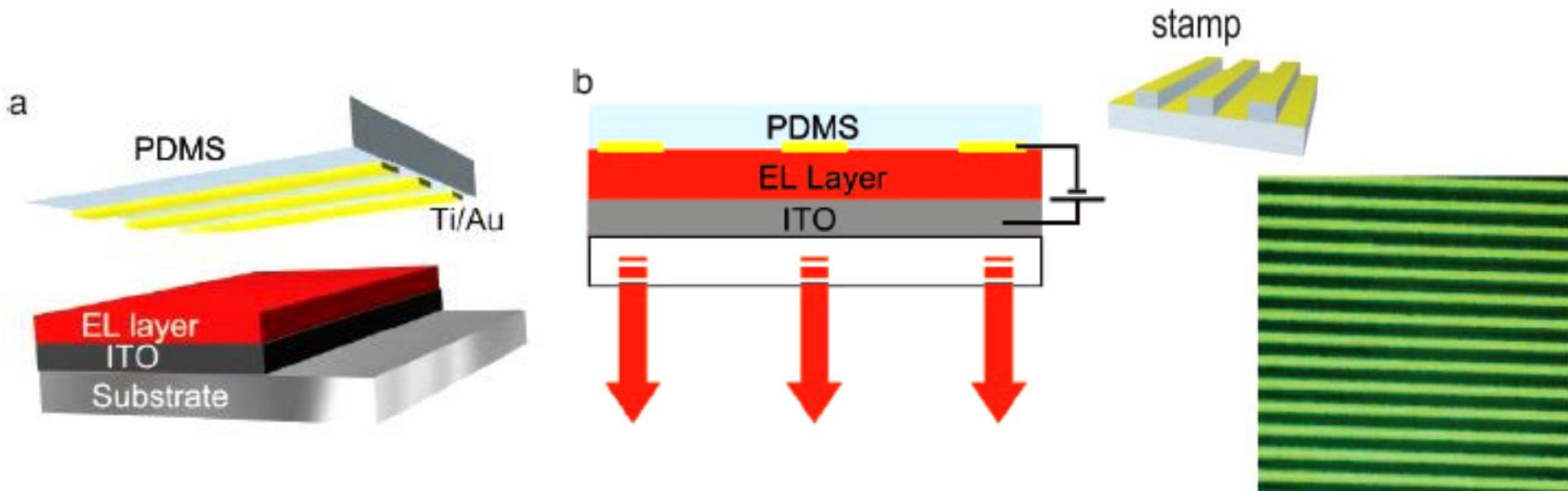
On PET



Printed capacitor on PET

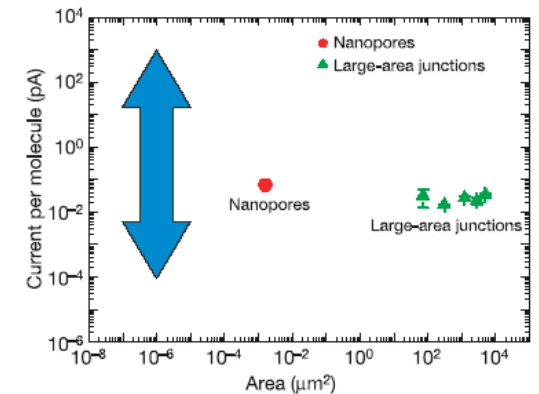
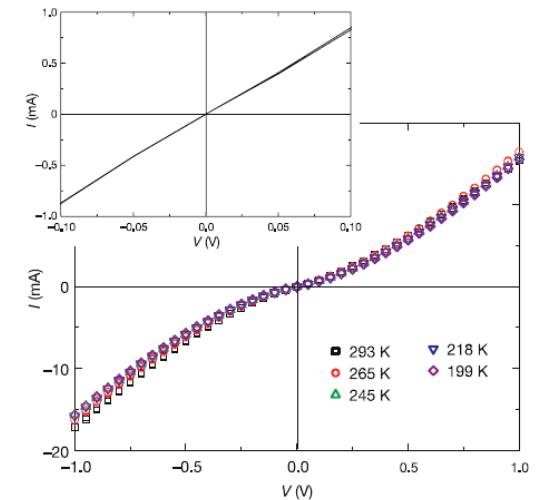
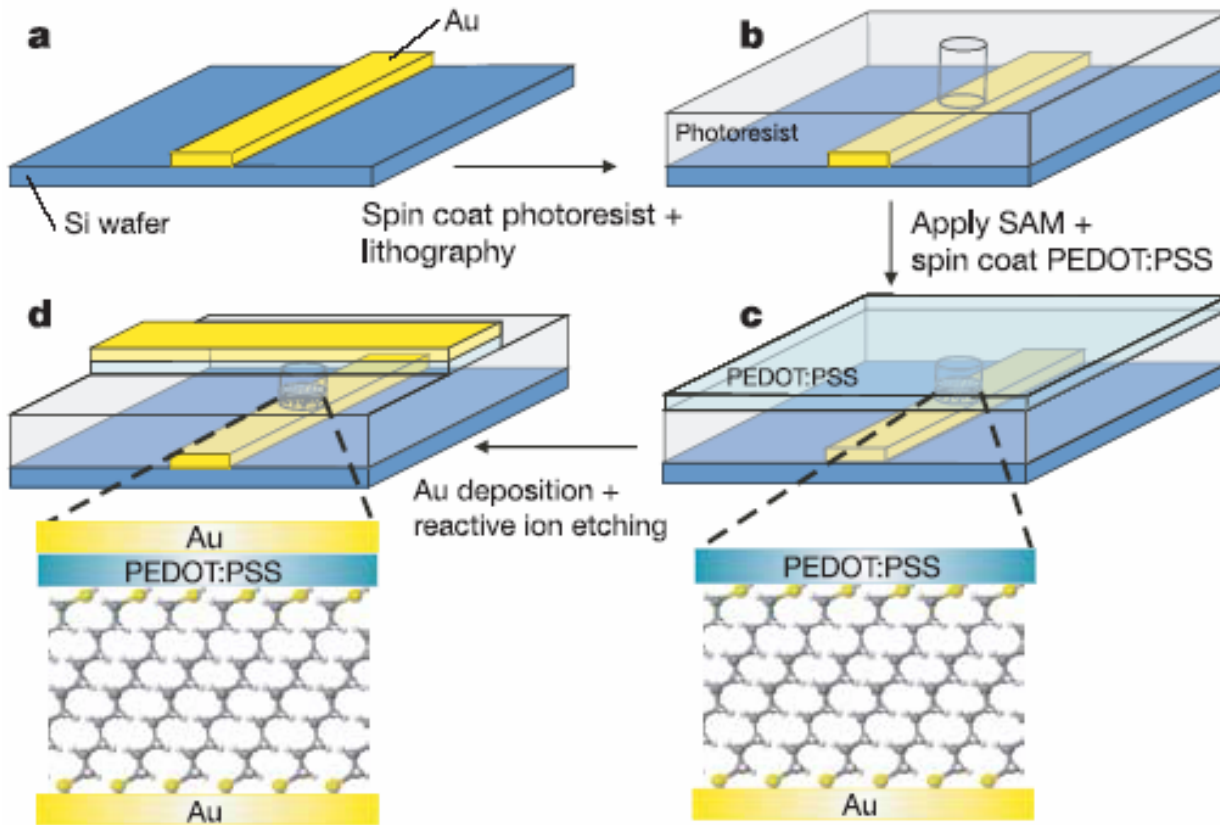


Soft Lithography for Organic Light-Emitting Diodes (OLEDs)



- Lamination of thin metal electrodes on an electroluminescent organic.
- van der Waals interactions establish intimate contacts.
- Reduced sensitivity to pinhole defects.
- Patterned OLEDs with sub-100 nm features.
- High performance displays and memory.

SAMs Molecular Junctions for Molecular Electronics



SAMs Molecular Junctions for Molecular Electronics

